

**AMENDMENTS TO THE CLAIMS:**

Without prejudice, this listing of claims will replace all prior versions and listings of the claims in the present application:

**LISTING OF CLAIMS:**

1-10. (Canceled).

11. (Currently Amended) A pressure sensor comprising:  
a pressure sensor element having a diaphragm area; and  
a first fixing area, a pressure to be measured exerting a force action on the diaphragm area, the first fixing area being connected to a second fixing area of a fixing element to fix the pressure sensor element;

wherein the first fixing area and the second fixing area are pressure-loaded by the force action, and

wherein a cross section of the fixing element tapers, at the second fixing area, at an angle to a sensing plane of the diaphragm area.

12. (Previously Presented) The pressure sensor of claim 11, wherein the pressure sensor element is at least one of made of a semiconductor material and is manufactured using bulk micromechanics.

13. (Previously Presented) The pressure sensor of claim 11, wherein the pressure sensor handles high pressures, including pressures up to approximately 1,000 bar.

14. (Previously Presented) The pressure sensor of claim 11, wherein the pressure sensor handles pressures exceeding 1,000 bar.

15. (Previously Presented) The pressure sensor of claim 11, wherein the fixing element, with respect to its coefficient of thermal expansion, is adapted to the sensor element.

16. (Previously Presented) The pressure sensor of claim 11, wherein a connecting material is between the first fixing area and the second fixing area, the connecting material being comparatively soft.
17. (Previously Presented) The pressure sensor of claim 11, wherein resistor elements are provided in the diaphragm area.
18. (Canceled).
19. (Currently Amended) The pressure sensor of claim 11, wherein a connecting surface between the first fixing area and the second fixing area is at an acute angle to the sensing a diaphragm plane of the diaphragm area.
20. (Canceled).
21. (New) The pressure sensor of claim 11, wherein the tapering of the cross section of the fixing element at the second fixing area centers the pressure sensor element in the fixing element under the force action of the measured pressure.
22. (New) The pressure sensor of claim 11, wherein the pressure sensor has an angled edge at the first fixing area which substantially conforms to the taper of the cross section of the fixing element at the second fixing area.
23. (New) The pressure sensor of claim 11, wherein the diaphragm area is formed as a wall of a cavity in the pressure sensor element, the cavity having additional walls adjacent to the diaphragm area and at an angle of substantially 90° to the diaphragm area.
24. (New) The pressure sensor of claim 25, wherein the pressure sensor element comprises silicon and the fixing element comprises Kovar.